Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) Movement detector having six degrees of freedom comprising a support ~~(1)~~ on which three position sensors ~~(2a), (2b) and (2c)~~ are arranged according to three orthogonal axes, each sensor comprising a rigid body ~~(3),~~ conducting areas ~~(6b)~~ arranged on the rigid body ~~(3)~~ and an electrically conducting deformable element ~~(4)~~ presenting a rest position in which it is isolated from the conducting areas ~~(6b)~~, and moving from the rest position to an active position in response to a high-speed movement of predetermined direction and orientation, detector ~~characterized in that~~ wherein each sensor ~~(2a, 2b, 2c)~~ comprises four conducting areas ~~(6b),~~ arranged two by two on two opposite inside walls of the rigid body ~~(3),~~ and that the deformable element ~~(4)~~ associated with each sensor ~~(2a, 2b, 2c)~~ is in equilibrium around its central part, responds to a translation along a predetermined axis by bending causing a simultaneous and temporary contact of its ends with the two conducting areas ~~(6b)~~ of one and the same inside wall and responds to a rotation around a predetermined axis by a pivoting causing a simultaneous and temporary contact of its ends with two conducting areas ~~(6b)~~ arranged on opposite inside walls.

2. (Currently Amended) Detector according to claim 1, ~~characterized in that it comprises~~ comprising an electronic processing circuit ~~(15)~~ connected to the conducting areas ~~(6b)~~ of the three sensors.

3. (Currently Amended) Detector according to ~~one of the claims 1 and 2~~ claim 1, ~~characterized in that~~ wherein the deformable element ~~(4)~~ is a beam in equilibrium around its transverse median axis.

4. (Currently Amended) Detector according to claim 3, ~~characterized in that~~ wherein the beam comprises conducting areas ~~(6a)~~ at the ends thereof.

5. (Currently Amended) Detector according to ~~one of the claims 1 and 2~~ claim 1, ~~characterized in that~~ wherein the deformable element ~~(4)~~ is a disc in equilibrium around its central axis.

6. (Currently Amended) Detector according to claim 5, ~~characterized in that~~ wherein the disc comprises a peripheral conducting area ~~(6a)~~ on each of its faces.

7. (Currently Amended) Detector according to ~~any one of the claims 1 to 6~~claim 1, ~~characterized in that~~ wherein the deformable element ~~(4)~~ is electrically connected to a power supply contact area ~~(10)~~ arranged on the rigid body ~~(3)~~ of the sensor.

8. (Currently Amended) Detector according to ~~any one of the claims 1 to 7~~claim 1, ~~characterized in that~~ wherein the deformable element ~~(4)~~ is in an equilibrium position corresponding to the rest position of the sensor for any movement the acceleration whereof is less than or equal to the force of gravity G.

9. (Currently Amended) Detector according to ~~any one of the claims 1 to 8~~claim 1, ~~characterized in that~~ wherein the rigid body of a sensor comprises two substrates ~~(7a) and~~

~~(7b)~~ arranged face to face, connected by balls ~~(8)~~ constituting an electrical interconnection between the conducting areas ~~(6b)~~ of one of the substrates ~~(7a)~~ and output electrical contact areas ~~(9)~~ formed on the other substrate ~~(7b)~~.

10. (Currently Amended) Detector according to claim 9, ~~characterized in that~~ wherein the deformable element ~~(4)~~ is formed by two deformable half-elements comprising a conducting layer ~~(12)~~, supported by a central pillar ~~(11)~~, formed on a central power supply contact area ~~(10)~~, formed on the corresponding substrate ~~(7a, 7b)~~.

11. (Currently Amended) Method for production of a sensor according to claim 10, ~~characterized in that it is~~ achieved by microelectronics techniques and comprises:

- formation on each of the substrates ~~(7a, 7b)~~ of conducting areas ~~(6b)~~, of power supply contact areas ~~(10)~~ and, on one of the substrates ~~(7b)~~, of output electrical contact areas ~~(9)~~,
- formation on each of the substrates ~~(7a, 7b)~~ of a central pillar ~~(11)~~, in contact with the power supply contact area ~~(10)~~ and supporting a conducting layer ~~(12)~~ designed to form a deformable half-element,
- installation of balls ~~(8)~~ on the output electrical contact areas ~~(9)~~,
- hybridization of the two substrates ~~(7a) and (7b)~~ arranged face to face.